Preliminary Amendment
Divisional Application of U.S.S.N. 09/928,126
Attorney Docket No.: ASC-025DV1
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## MARKED-UP VERSION OF AMENDED TITLE PAGE

PROCESS FOR PRODUCING SEMICONDUCTOR ARTICLE USING GRADED  $\mathsf{E}[\mathsf{X}]\mathsf{PITAXIAL} \; \mathsf{GROWTH}$ 

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## MARKED-UP VERSION OF AMENDED TITLE AND PARAGRAPH OF SPECIFICATION

Page 2, lines 1-2

PROCESS FOR PRODUCING SEMICONDUCTOR ARTICLE USING GRADED  $E[X]PIT\underline{AX}IAL$  GROWTH

Page 1, lines 5-6

This application is a divisional of application Serial No. 09/928,126, filed on August 10, 2001, which claims priority from provisional application Ser[.]ial No. 60/225,666, filed August 16, 2000, now expired, the entire disclosures of which are incorporated by reference herein.

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## MARKED-UP VERSION OF AMENDED CLAIMS

- 54. (Amended) A semiconductor structure comprising:
  - a [first semiconductor] substrate including an insulator layer;
- a [second]<u>first</u> layer of relaxed  $Si_{1-x}Ge_x$  <u>disposed over the insulator layer</u>, wherein x = has a value in the range of 0.1 to 1; and
- a [third] second layer disposed over the substrate, the second layer comprising [at least one of ]a material selected from the group consisting of GaAs, AlAs, ZnSe, [and ]InGaP, [or ]and strained Si<sub>1-y</sub>Ge<sub>y</sub> [wherein  $y \neq x$ ]wherein  $y \neq x$ ]wherein  $y \neq x$ ] wherein  $y \neq x$ ] w
- 55. (Amended) A semiconductor structure comprising:
  - a [first] substrate[comprising monocrystalline silicon substrate];
  - a plurality of layers disposed over the substrate, the layers comprising:
  - a [second layer of ]graded  $Si_{1-x}Ge_x$  buffer layer, [wherein said] the graded buffer layer having a Ge concentration x, wherein x has a value that [is ]increase[d]s from zero to a value y;
    - a [third layer of ]first\_relaxed [Si<sub>1-y</sub>Ge<sub>y</sub>]layer comprising Si<sub>1-y</sub>Ge<sub>y</sub>; and
  - a [fourth strained or defect] <u>separation</u> layer <u>comprising at least one</u>

    <u>material selected from the group consisting of [comprising either a ] strained Si<sub>1-z</sub>Ge<sub>z</sub> [layer] with  $z \neq y$ , [or other ]III-V <u>materials, [or ] and II-VI materials [; and ]</u></u>

[a fifth relaxed layer comprising either a relaxed Si<sub>1-w</sub>Ge<sub>w</sub> layer where w is close or equal to y, or, when y is equal to 1, at least one of Ge, GaAs, AlAs, ZnSe and InGaP].